



*C-AD Machine Advisory Committee Meeting (MAC-20),
Dec 19-21, 2023*



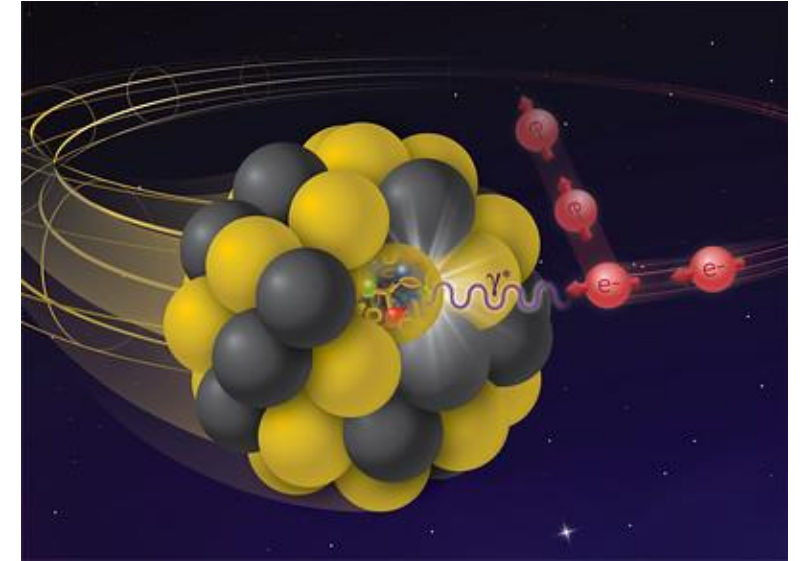
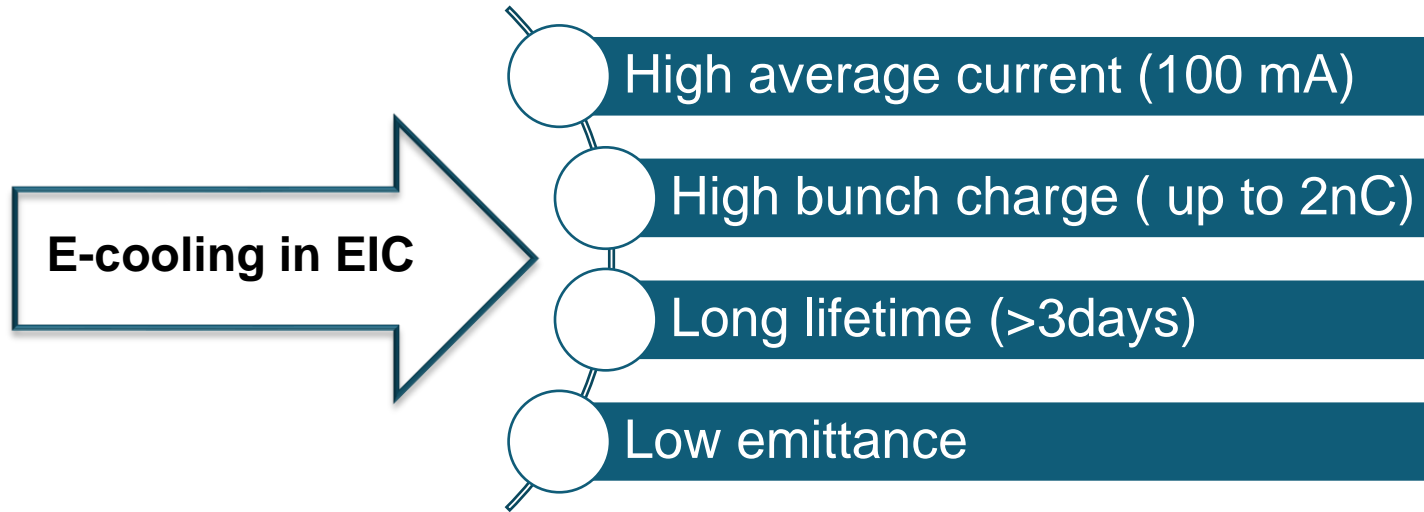
R&D for high intensity electron sources in support of EIC (ECA FOA)

Mengjia Gaowei on behalf of the collaboration
Collider Accelerator Department, BNL



@BrookhavenLab

Introduction: electron cooling for EIC



Electron cooling is a promising technique to improve the luminosity of the hadron beams by balancing emittance growth rates due to intrabeam scattering (IBS).

At RHIC, Both the low energy and high energy electron cooling project, LEReC and CeC, are currently using the bi-alkali antimonide photocathodes to generate electrons.

Current state-of-the-art/practice

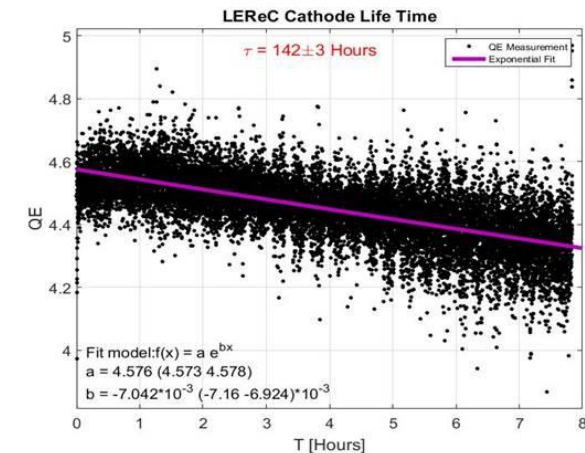
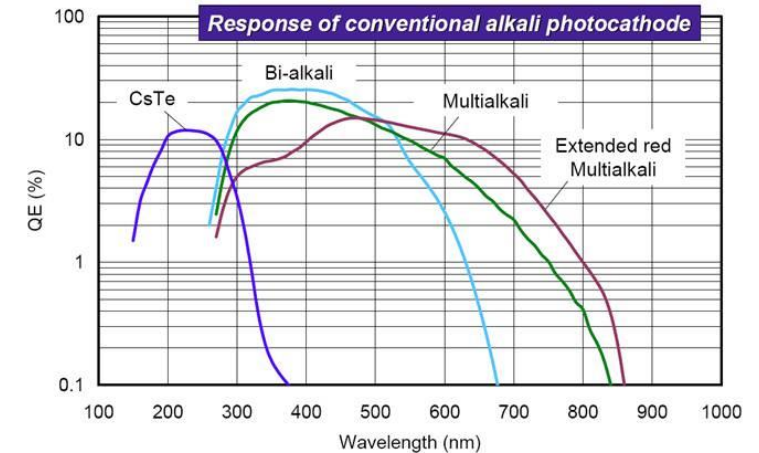
Excellent photocathode for electron cooling: good combination of properties

High quantum efficiency in visible light range
Less sensitive to vacuum than GaAs:Cs

Has been demonstrated in practice

Cornell University: 65 mA, 60 pC bunch charge for 2 days
LEReC @ BNL: 50mA for hours; 15~20 mA average current for weeks of operation, and 20K C charge lifetime

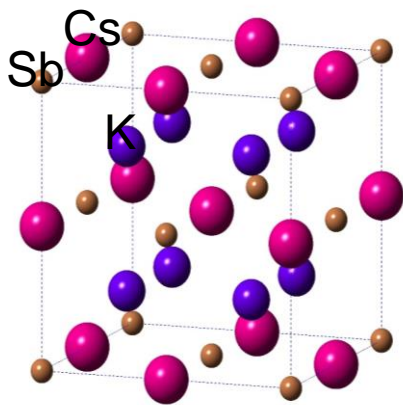
For semiconductor photocathodes, material properties like stoichiometry, crystallinity and surface roughness determines the performance merits such as quantum efficiency and thermal emittance. Our studies and experience show that our cathode material has a lot more to improve in terms of these properties.



25 mA;
t = 142 h;
QE > 4%

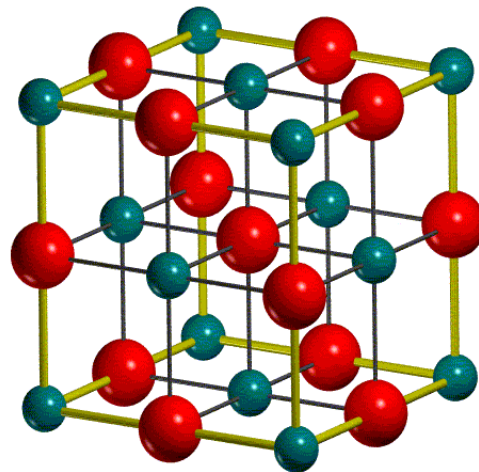
Epitaxial growth of alkali antimonide photocathode

- ❑ Epitaxy refers to the growth of a single crystalline film on a single crystalline substrate.
- ❑ Epitaxial Growth of Photocathode: Large grain or single crystal photocathode that has smooth surface; low scattering rate from reduced grain boundaries → low mean transverse energy and high QE
- ❑ 2 key aspects to epitaxial growth: lattice matched substrates and co-evaporation.

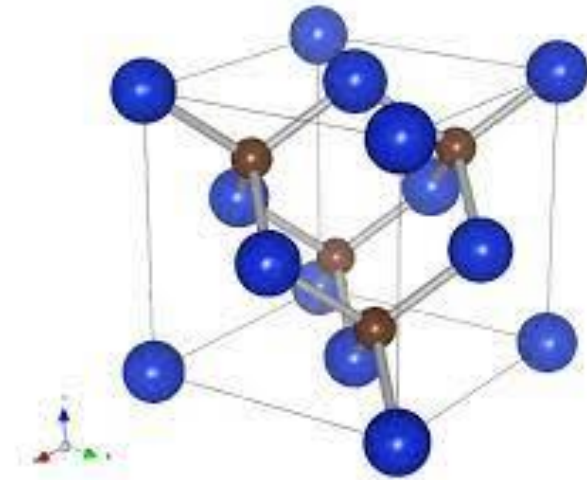


K₂CsSb unit cell

K₂CsSb, Cs₃Sb: b.c.c. crystal structure
Lattice parameter: 8.615 Å, 9.18 Å



MgO: f.c.c. crystal structure
Lattice parameter: 4.21 Å



3C-SiC: f.c.c. crystal structure
Lattice parameter: 4.35 Å

Cathode Material development

- **Epitaxial growth of single crystal cathode material**
- **Upgrade with RHEED**
- **Bulk single crystal growth**

Transfer system development

- **Existing design and experience**

High current test

- **High current test chamber**
- **Gun test in tunnel**
- **Material characterization for degraded cathodes**

Project tasks and timeline

Tasks	Year 1				Year 2				Year 3				Year 4				Year 5				
	Q1	Q2	Q3	Q4	Q1	Q2	Q3	Q4	Q1	Q2	Q3	Q4	Q1	Q2	Q3	Q4	Q1	Q2	Q3	Q4	
Single crystal photocathode development	█																				
Upgrade growth chamber with RHEED	█																				
Incorporate in situ characterization with offline technique					█																
Measure the transverse emittance of the electron beam generated by the single crystal photocathode													█								
Compare emittance measurements with simulations																	█				
Fabricate cathode transfer chamber between growth and analysis tools	█																				
Commission the transfer chamber									█												
Lifetime test for single crystal cathode and the traditionally grown cathode under high current condition													█				█				
Characterize damaged cathodes in the analysis chamber and investigate recovering methods															█				█		
Test synthesized bulk cathode under high current conditions															█						
Test cathodes with 2-D protective coating under high current conditions																	█				

- Tasks year 1 (2021/8 ~ 2022/7)
 - Single crystal photocathode development
 - Upgrade growth chamber with RHEED
 - Fabricate cathode transfer chamber between growth and analysis tools (design stage)
- Tasks year 2 (2022/8 ~2023/7)
 - Single crystal photocathode development
 - Incorporate in situ x-ray characteristics with offline technique.
 - Fabricate cathode transfer chamber between growth and analysis tools

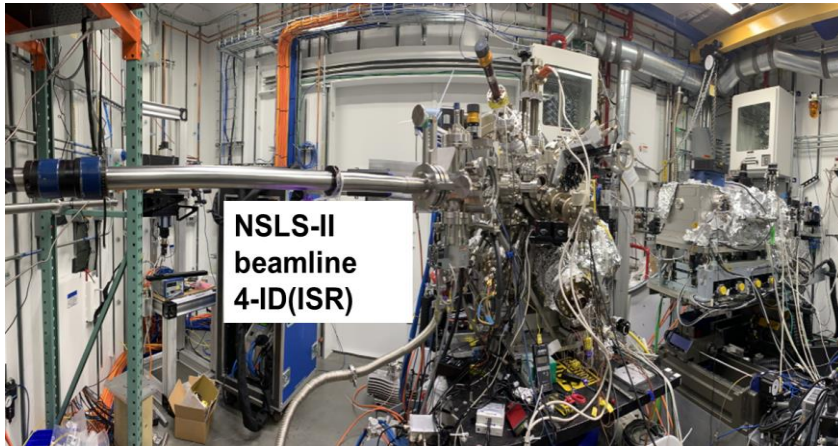
Hardware upgrade:

- **RHEED** system has been installed, commissioned on the cathode growth chamber. RHEED measurement was successfully performed during the NSLS-II beamline along with the x-ray characterization for the epitaxial growth of the photocathode material.
- Chamber was also upgraded to use **pulsed laser deposition (PLD)** as the growth method. Rotatable PLD target was installed and optics were build to introduce the excimer laser into the chamber.

Material development:

- **Epitaxial growth of K_2CsSb , Cs_3Sb and Cs_2Te** were performed on various lattice matched substrates. High quantum efficiency, ultrasmooth and epitaxial thin film photocathodes are achieved.

Experimental: characterization



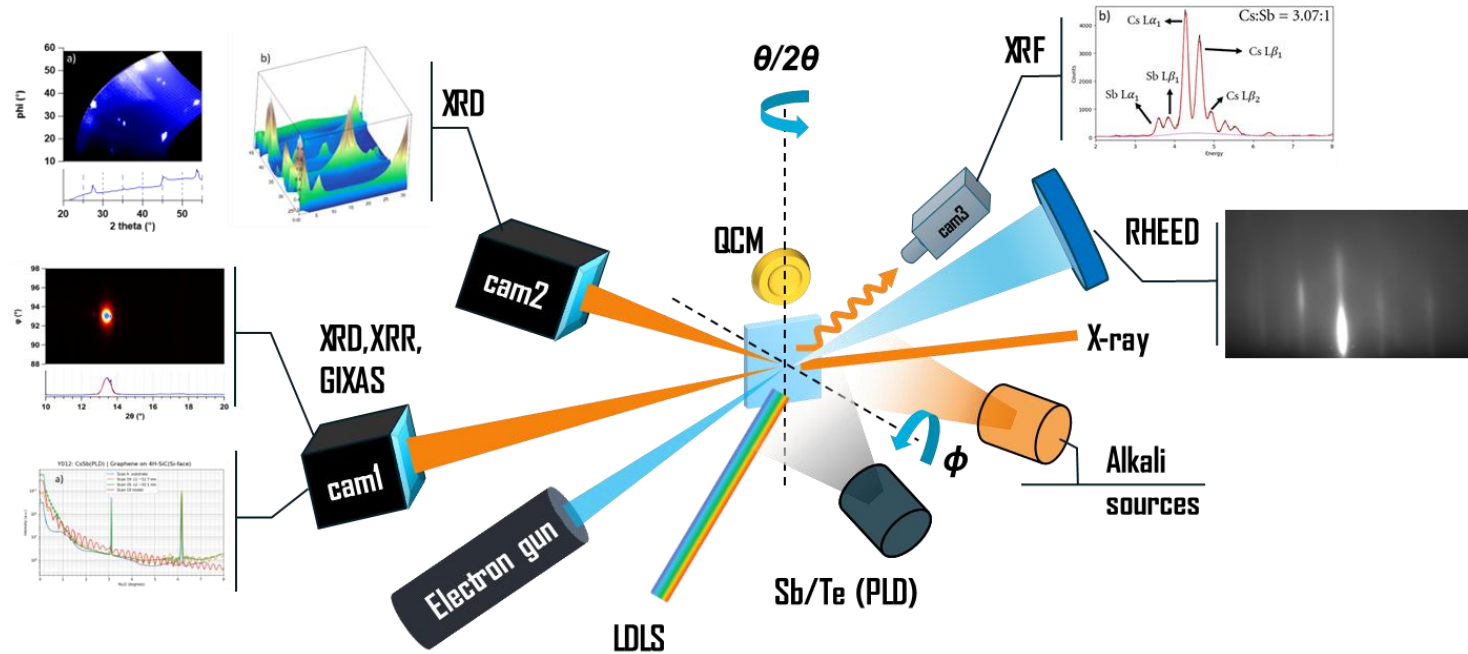
NSLS-II
beamline
4-ID(ISR)

Evaporators:

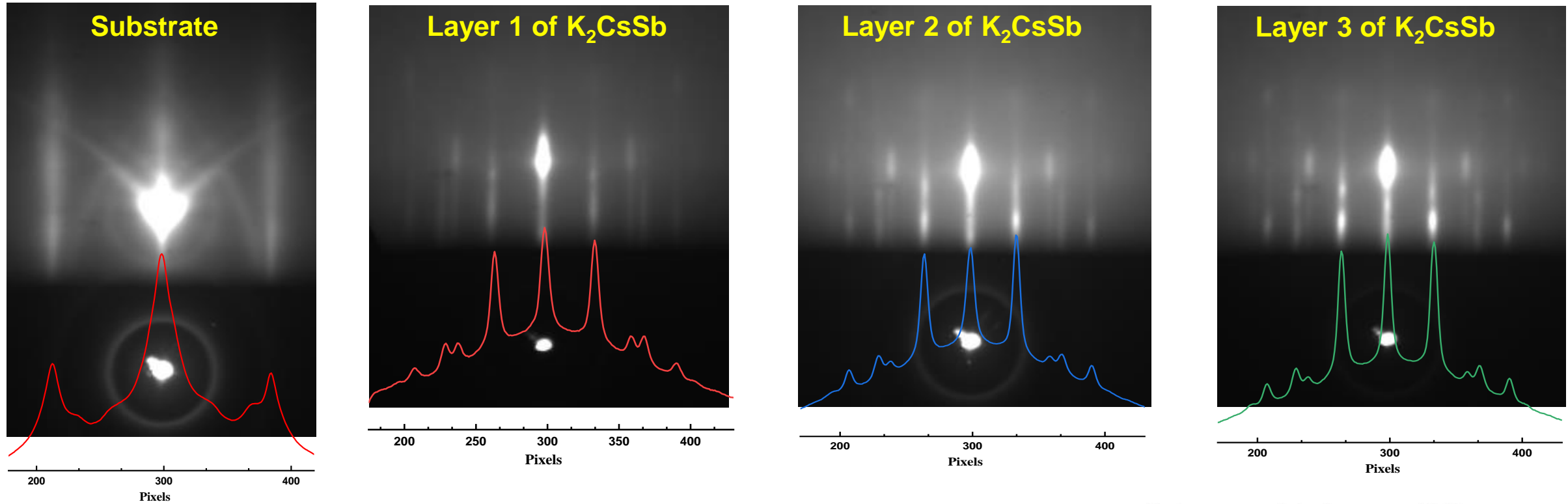
- Thermal Sb/Te
- Alkali metals
- PLD Sb/Te

Characterization:

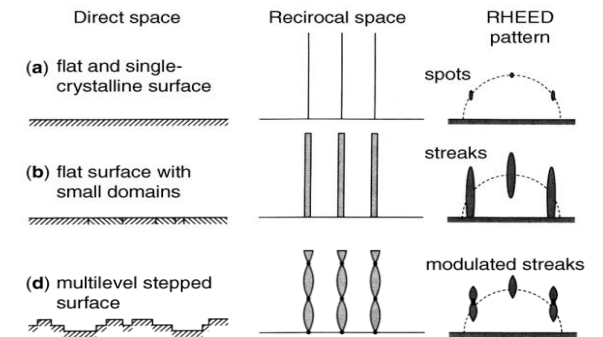
- QCM
- XRD
- XRR
- XRF
- QE
- RHEED



Epitaxial K_2CsSb : RHEED



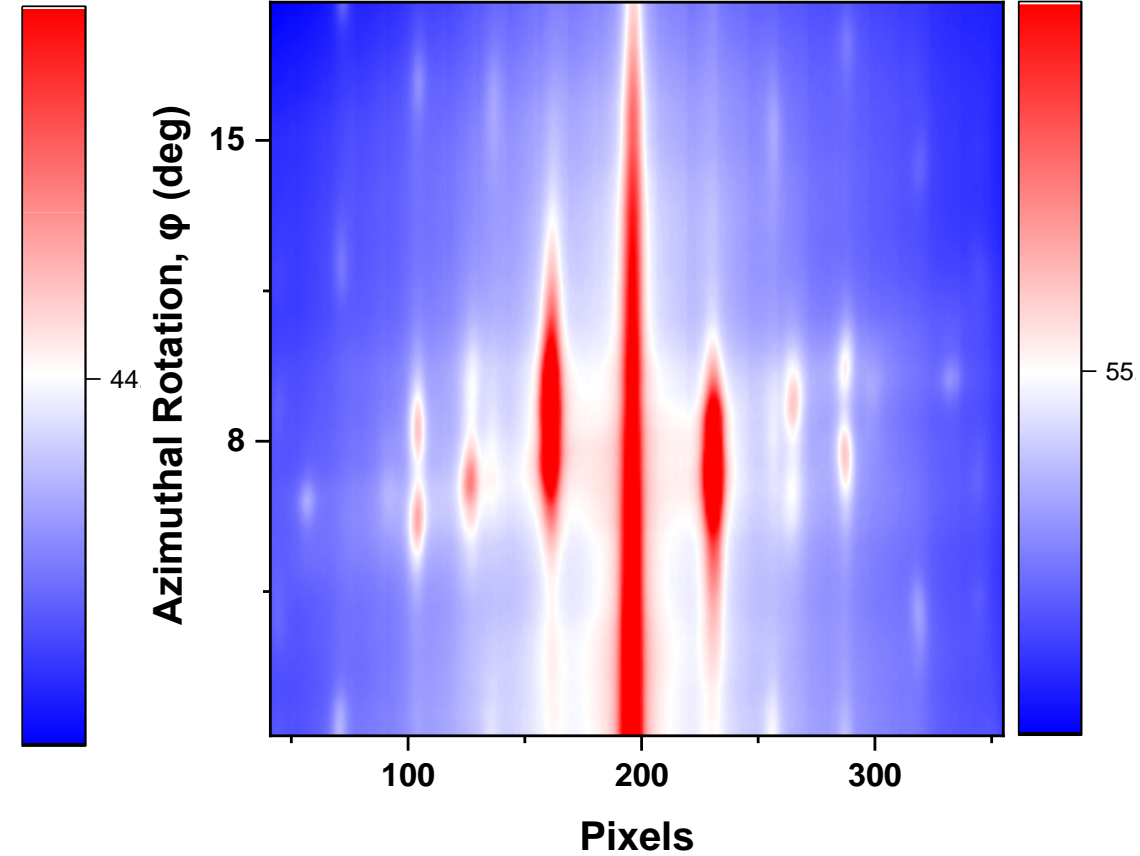
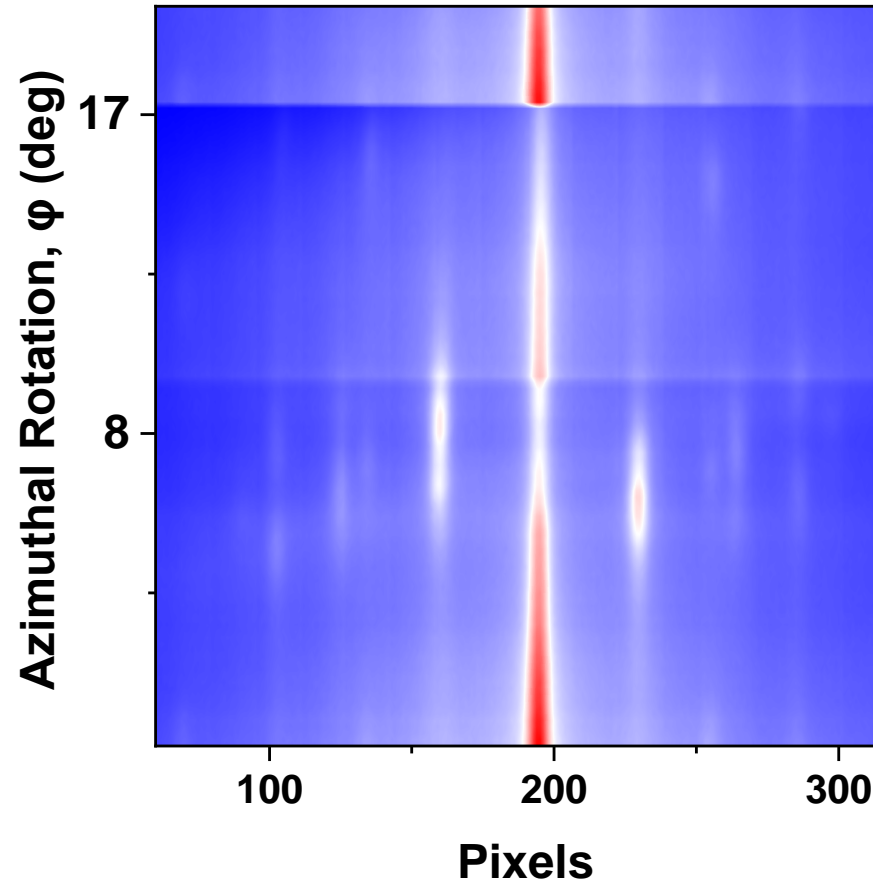
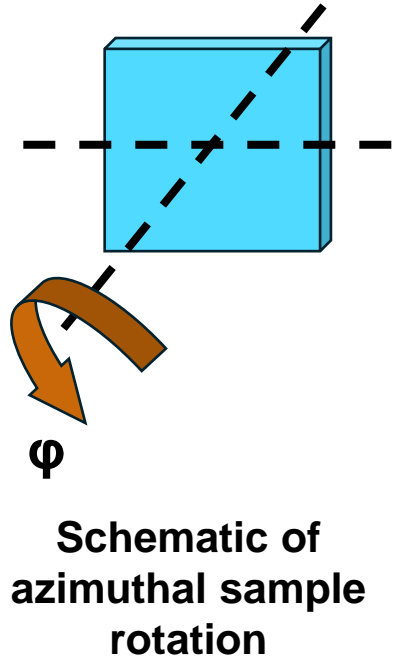
- ❑ Alignment with substrate peaks indicating epitaxy.
- ❑ Streaky pattern represent smooth surfaces with small domains.
- ❑ Multiple sets of streaks visible, indicating multiple grain orientations.
- ❑ Modulated streaks: roughness increases.



Epitaxial K_2CsSb : RHEED

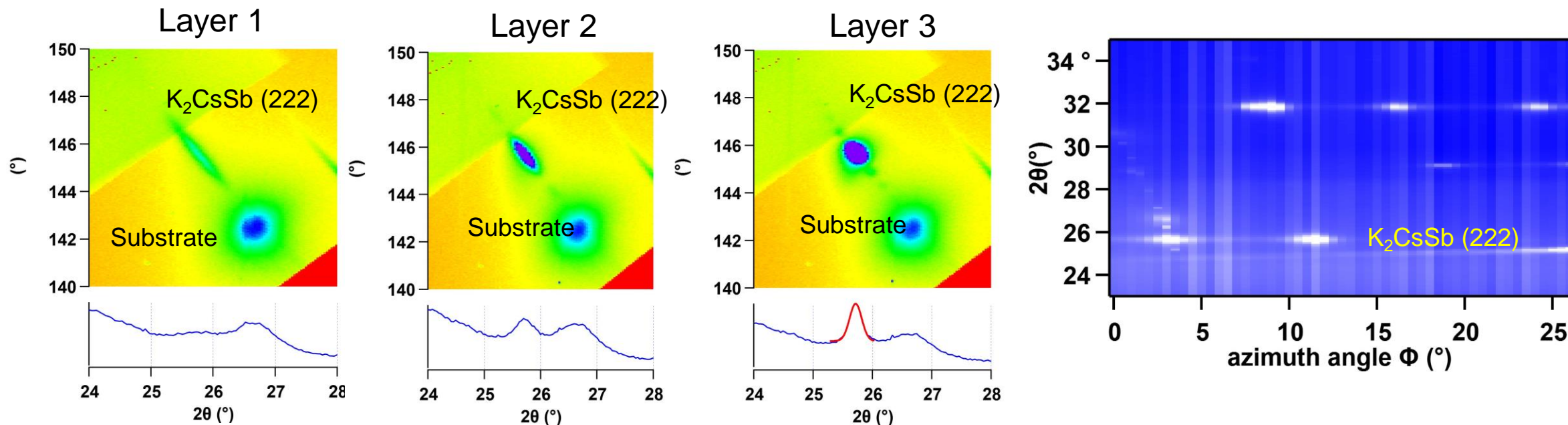
Layer 1 of K_2CsSb

Layer 3 of K_2CsSb



Azimuthal angular dependence in RHEED pattern are observed, indicating aligned crystalline domains are formed in the cathode film.

Epitaxial K_2CsSb : bulk crystallinity

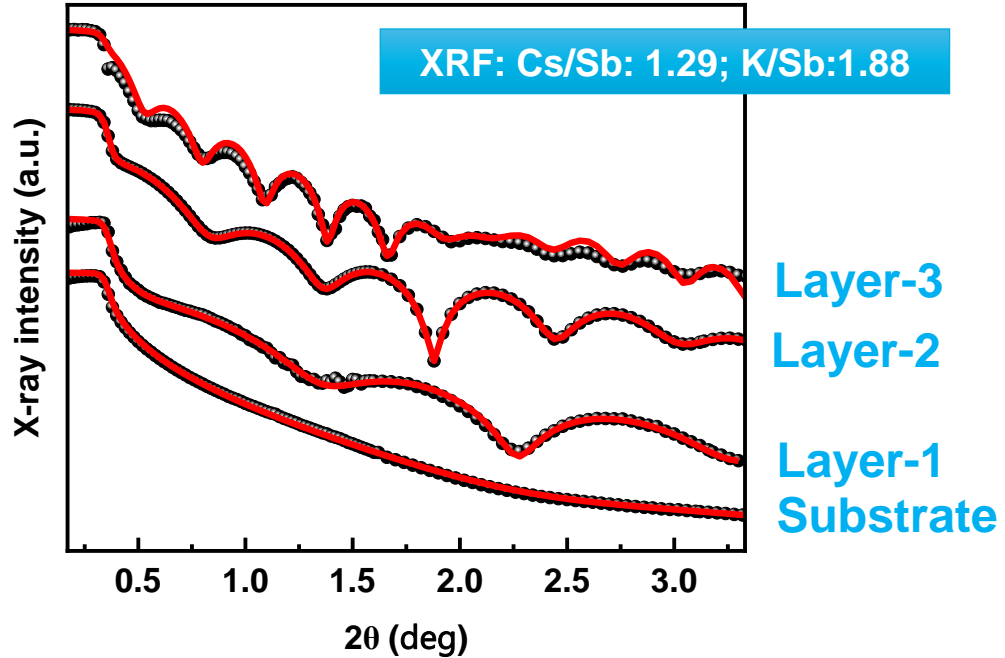


$x_0 = 25.715 \pm 0.00224$
width = 0.14515 ± 0.00415
Grain size: 411.30 nm
Film thickness Layer 3 : 20 nm

Diffraction image at Bragg condition (222)
Elongation structure is from Mosaicity and strain of the film.
Grain size is \gg film thickness; indicating the formation of large crystal domains.

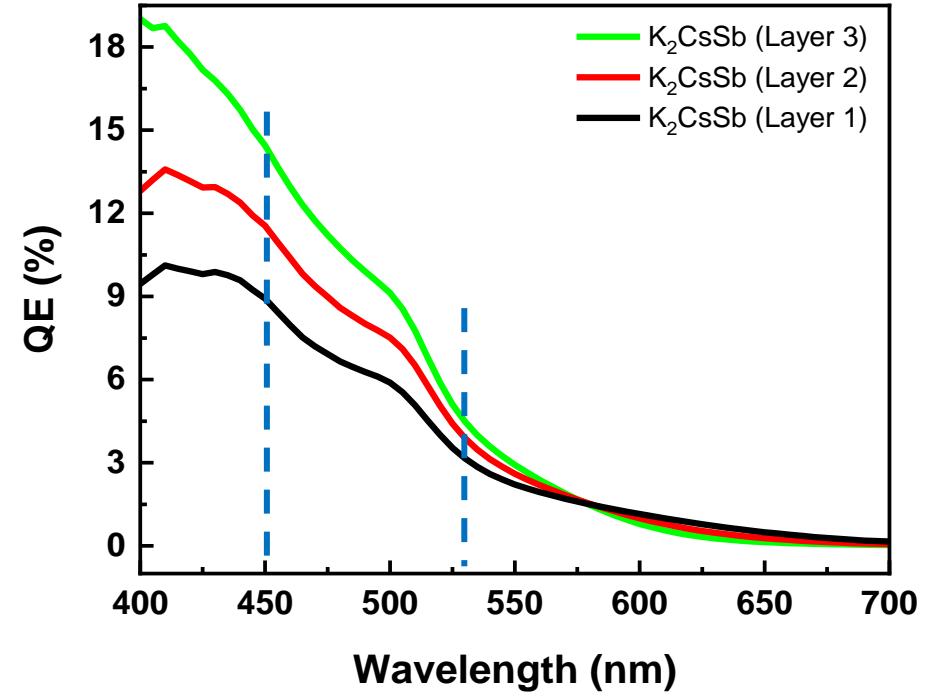
Azimuthal angular dependence from XRD is observed, agrees with RHEED. Indicating the crystalline grains are aligned in orientation.

Film roughness and QE



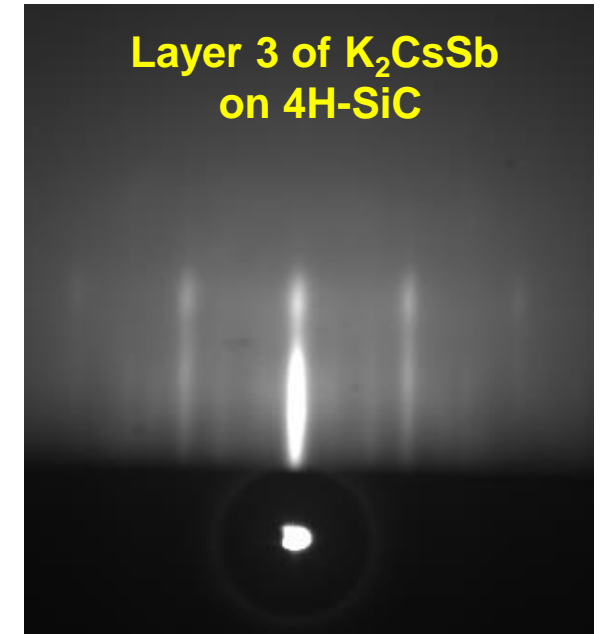
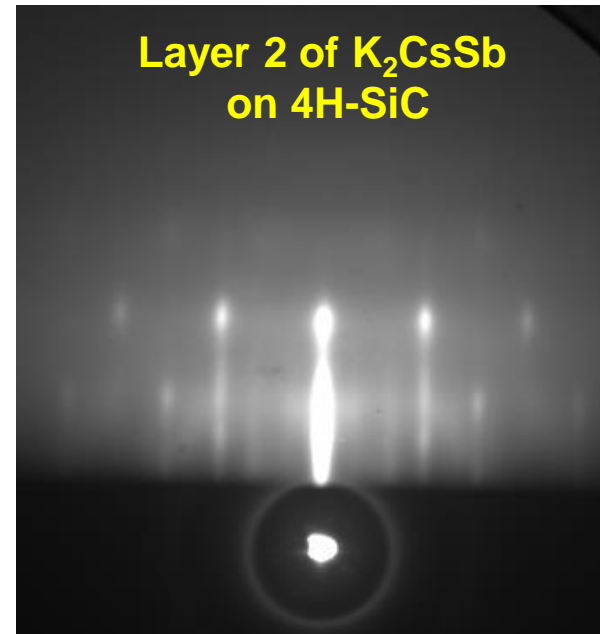
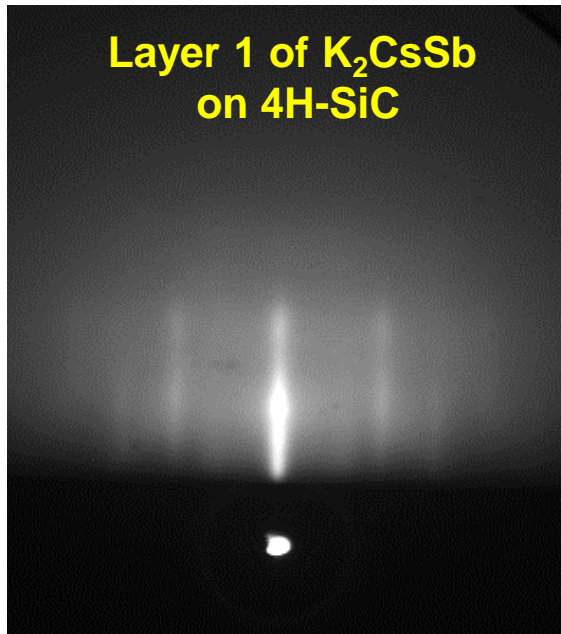
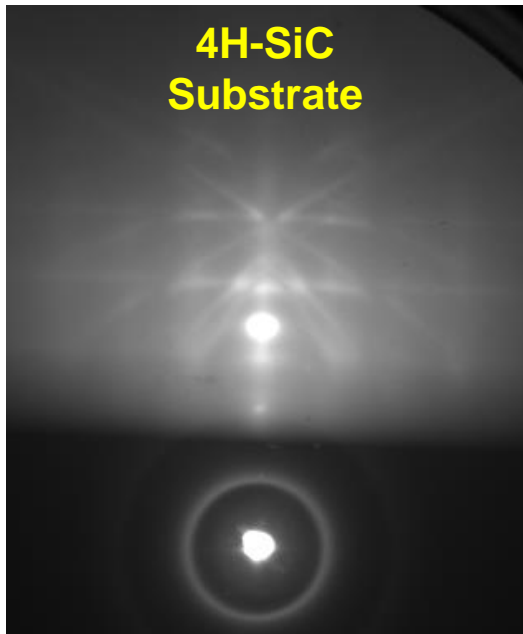
XRR	Thickness (nm)	Roughness (nm)
Substrate	NA	0.40
Layer 1	6	0.60
Layer 1+2	11	0.65
Layer 1+2+3	20	0.75

XRR of K_2CsSb
Roughness increased with increasing thickness of photocathode thin film.

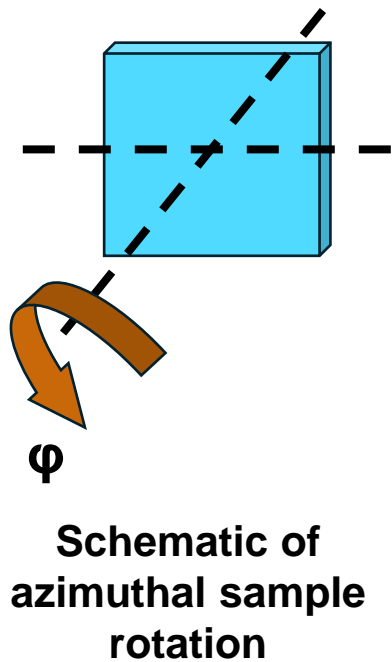


Wavelength (nm)	QE (%)		
	L1	L2	L3
450 (Blue)	8.9	11.6	14.5
530 (Green)	3.2	3.9	4.5

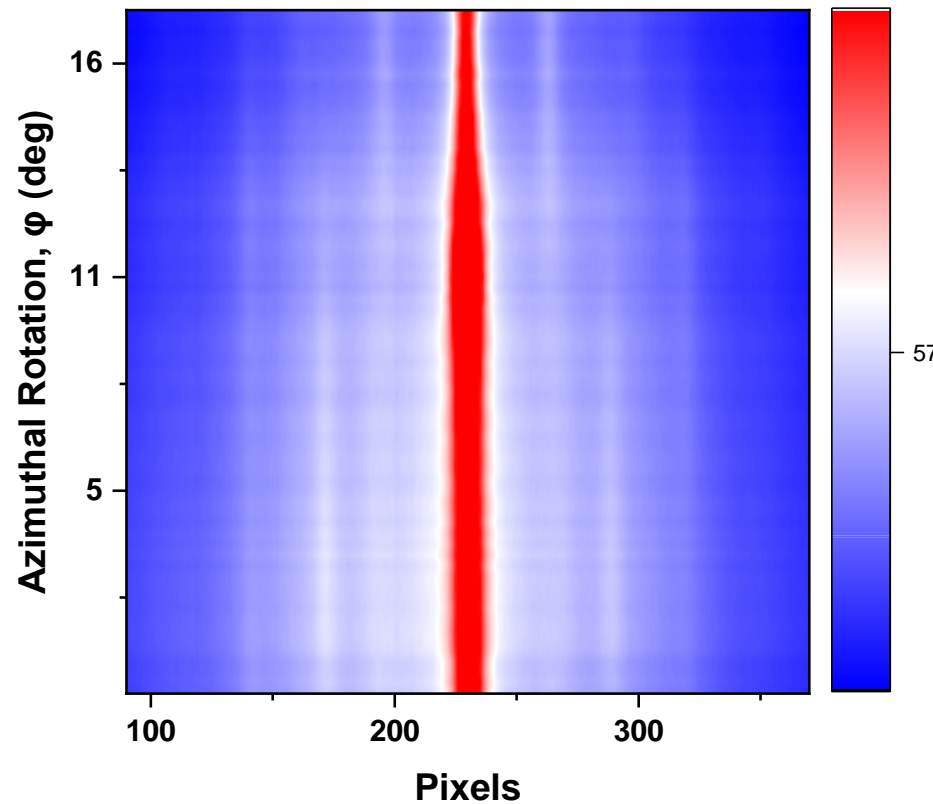
Offline test: K_2CsSb growth on doped 4H/SiC



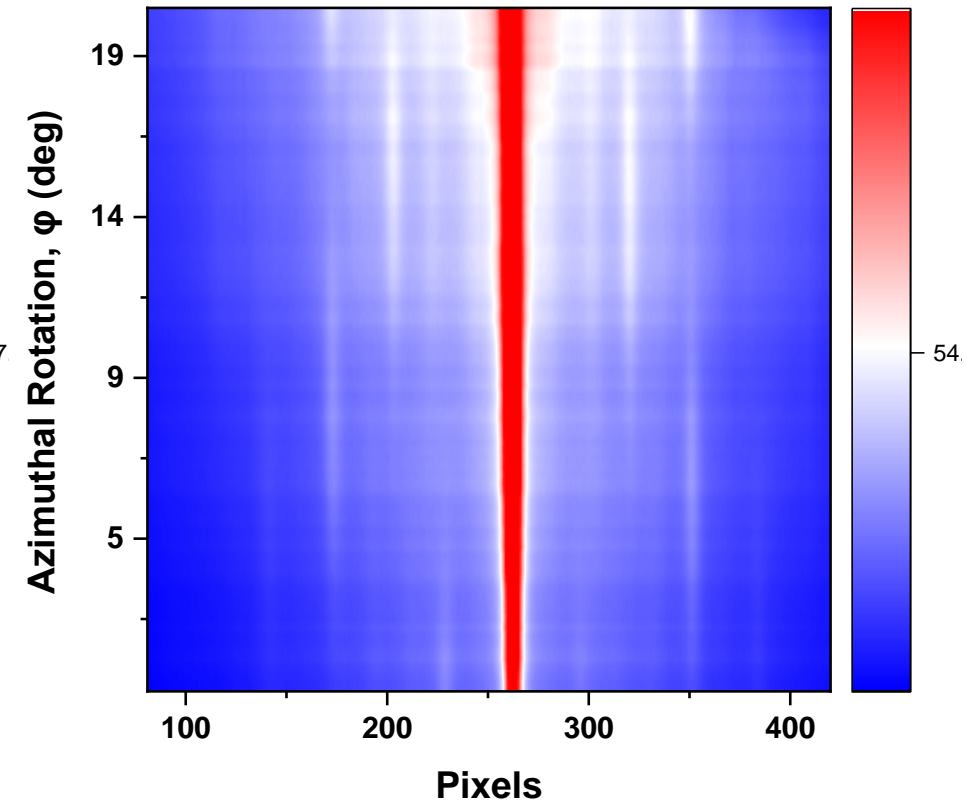
- Similar streaks to film in the x-ray experiment
- Streaky pattern represent smooth surfaces with small domains.
- Modulated streaks: roughness increases.



Layer 1 of K₂CsSb on 4H-SiC

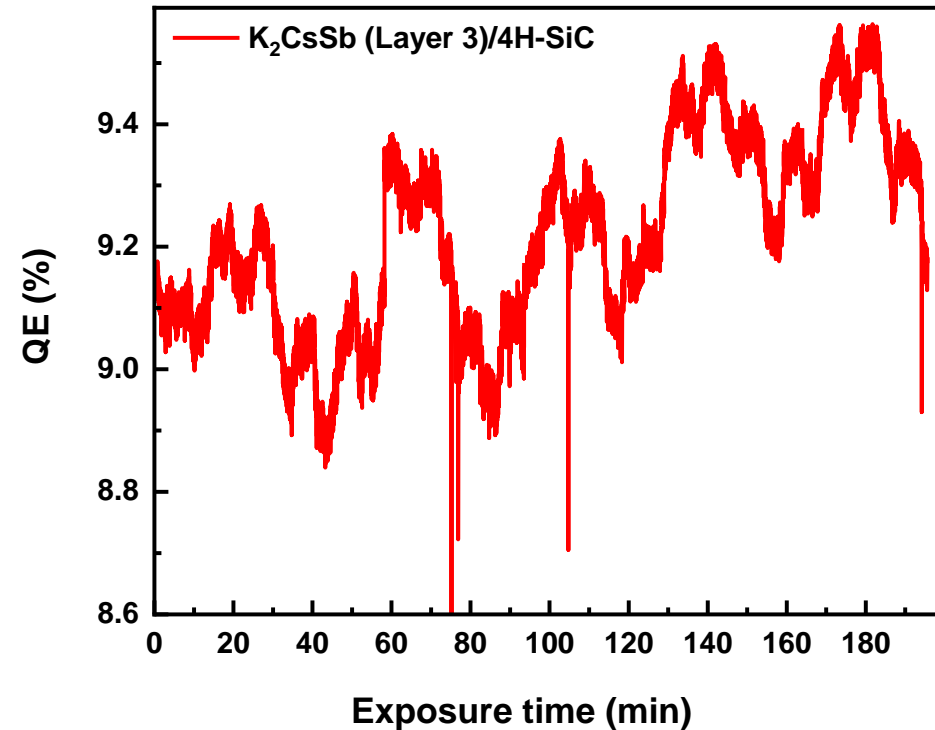
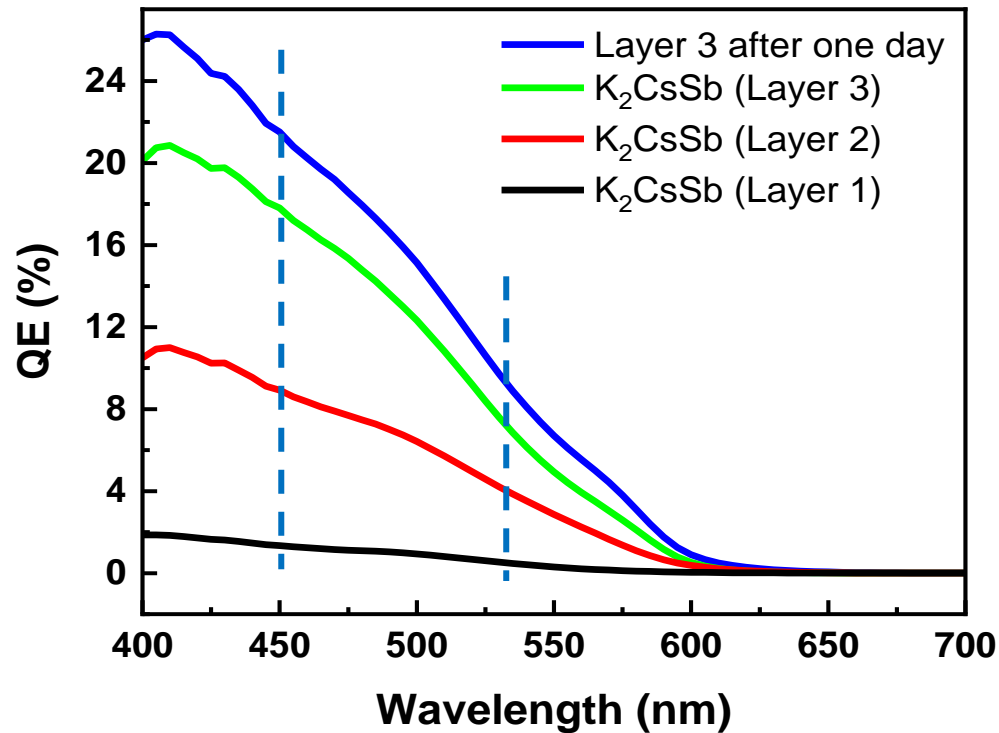


Layer 3 of K₂CsSb on 4H-SiC



Azimuthal angular dependence observed!

Quantum Efficiency



Wavelength (nm)		Sample-3 QE (%)			
		L1	L2	L3	L3 after 1 day
Green laser		0.5	4.6	9.2	--
LDLS source	450	1.3	8.9	17.8	21.5
	530	0.5	4.2	7.6	9.7

- Green QE is > 9% !
- Measured QE after 3-4 days of growth, no decay
- Current draw is about 25 uA
- Fluctuations are likely from laser power

Epitaxial growth of multiple alkali-based photocathode materials are achieved. The cathode films are showing exceptional performance in crystallinity, surface roughness and QE in a varied thickness range.

The plan forward is to: complete the transfer chamber and the system for emittance measurement, measure the emittance for epitaxial K_2CsSb ; gun test for high current performance; analysis for damaging mechanism to improve lifetime.

ACKNOWLEDGMENT: Work supported by Brookhaven Science Associates, LLC under Contract No. DE-SC0012704, DE-SC0013190 with the U.S. Department of Energy. The use of National Synchrotron Light Source II at Brookhaven National Laboratory is supported by U.S. Department of Energy Office of Science under Contract No. DE-AC02-98CH10886.

Thank you very much! Suggestions and comments are appreciated!

Back up slides

Epitaxial growth of alkali photocathode

A reflection high energy electron diffraction (RHEED) system is a standard in-situ diagnostic that is mainly sensitive to the film surface structure, can provide qualitative information on the growth mode such as island nucleation, texture and crystallinity.

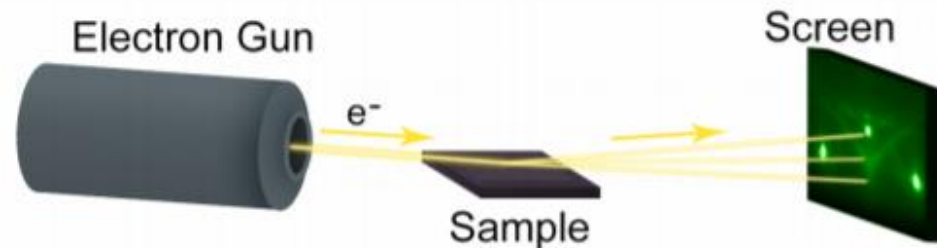
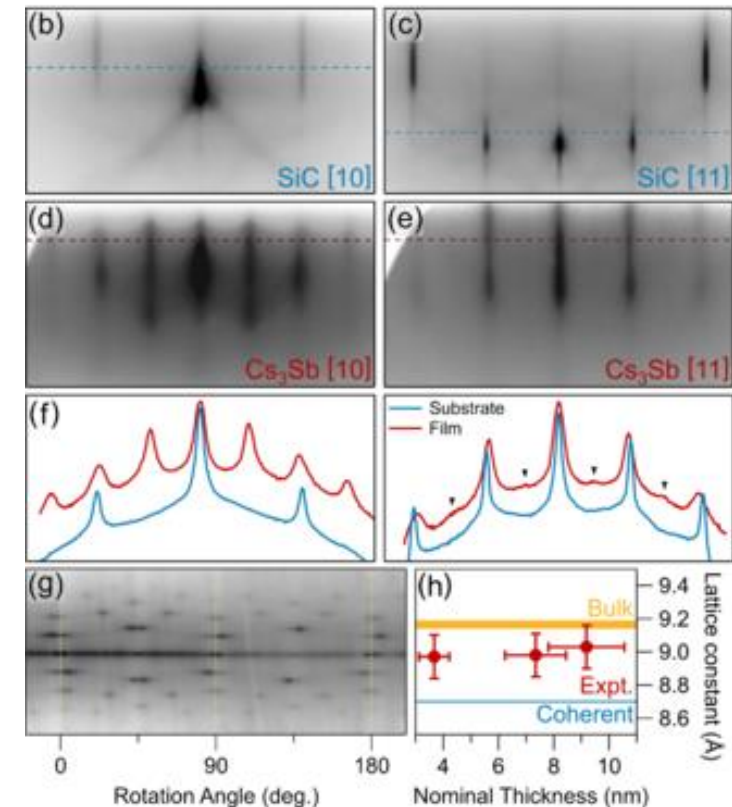


FIG. 1. The simplest RHEED set up includes an electron gun, a sample, and a fluorescence screen across from the gun.

RHEED: $\text{Cs}_3\text{Sb}/3\text{C-SiC}$



Reference:

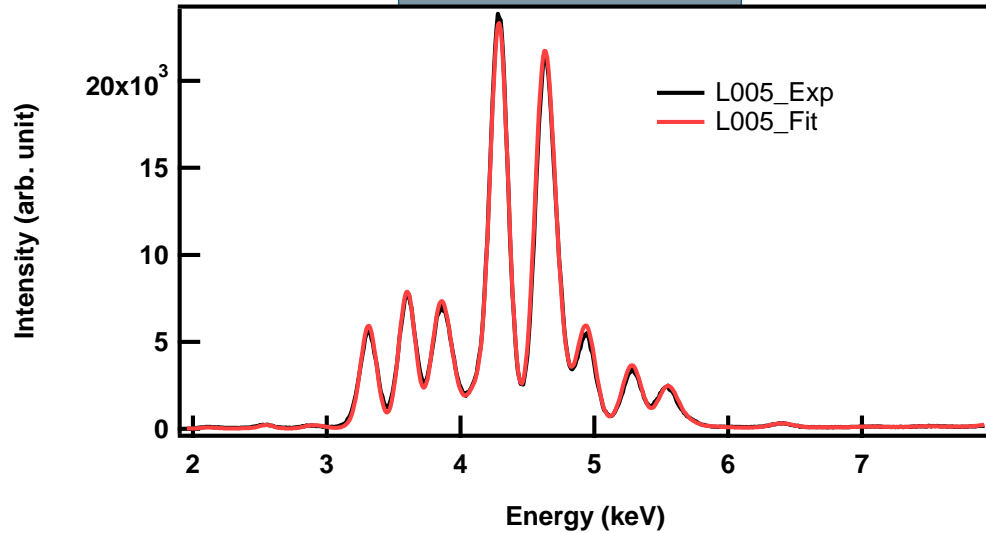
Reflection High-Energy Electron Diffraction, Nassim Derriche et al, 2019

Shuji Hasegawa. Characterization of Materials (Second Edition), chapter Reflection High-Energy Electron Diffraction, pages 1925–1938. 2012.

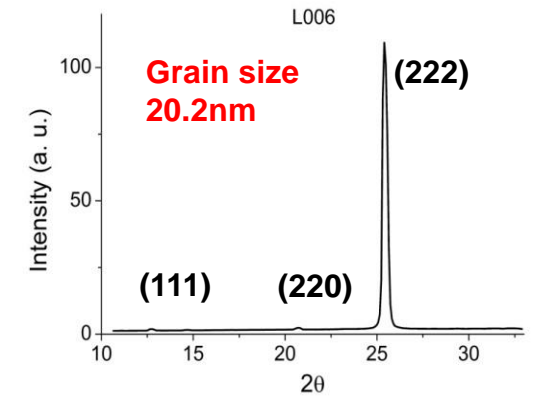
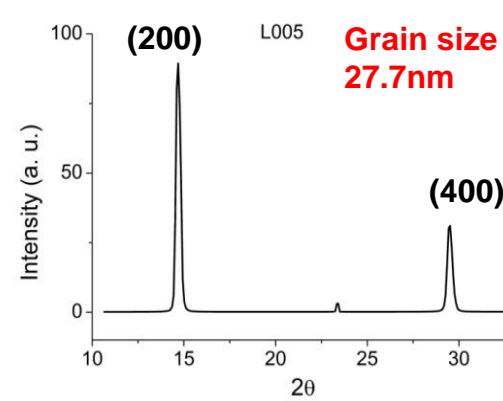
C. T. Parzyck, et al
Phys. Rev. Lett. 128, 114801, 2022

Co-evaporation for epitaxial growth: stoichiometric thin film growth in one step

XRF analysis



XRD: Camera 1

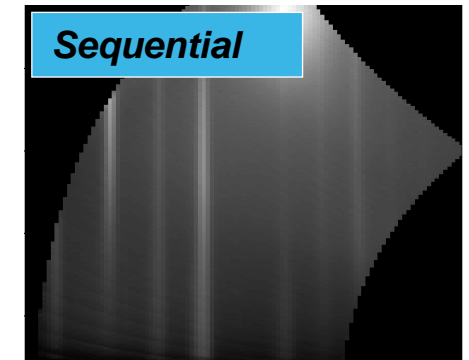
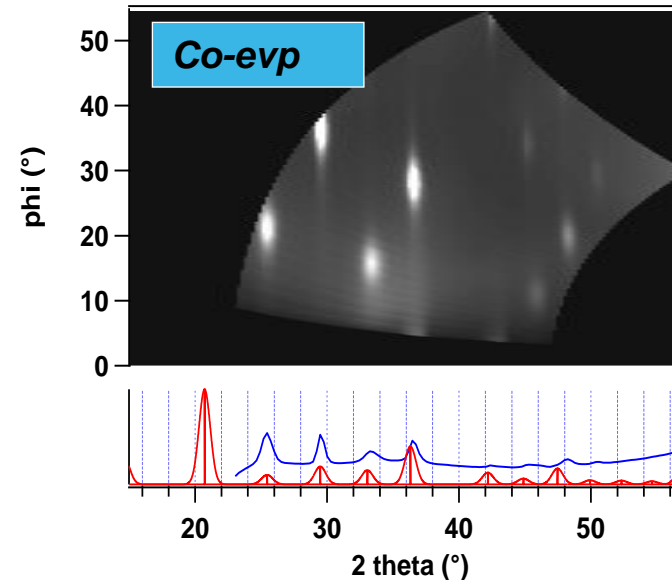


XRD: Camera 2

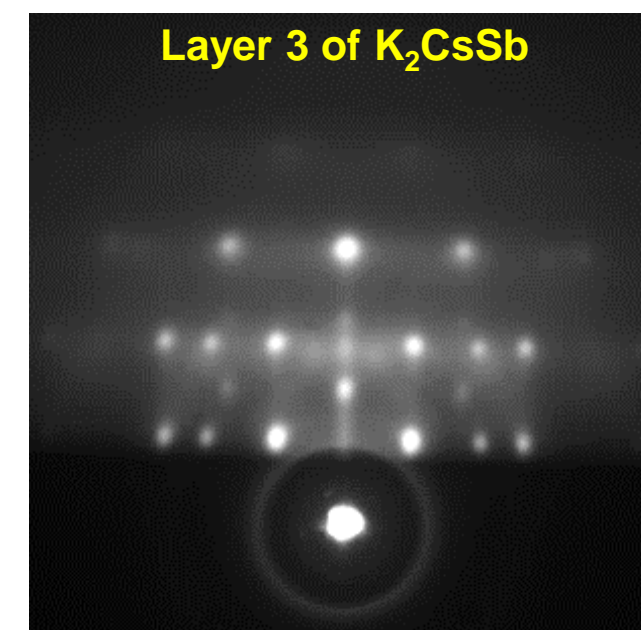
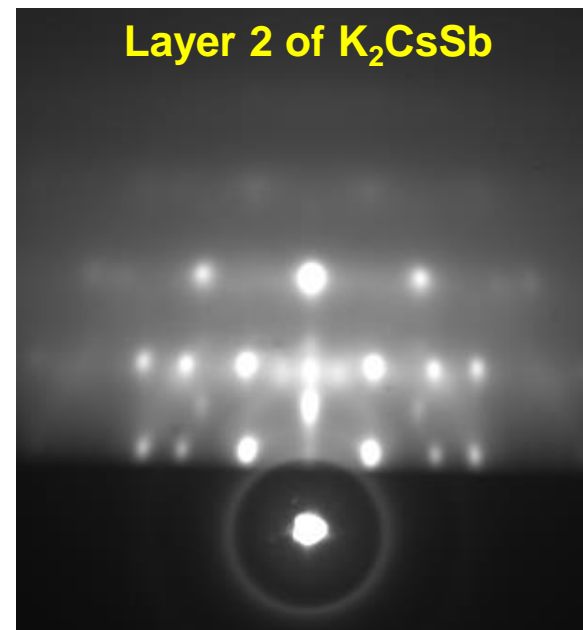
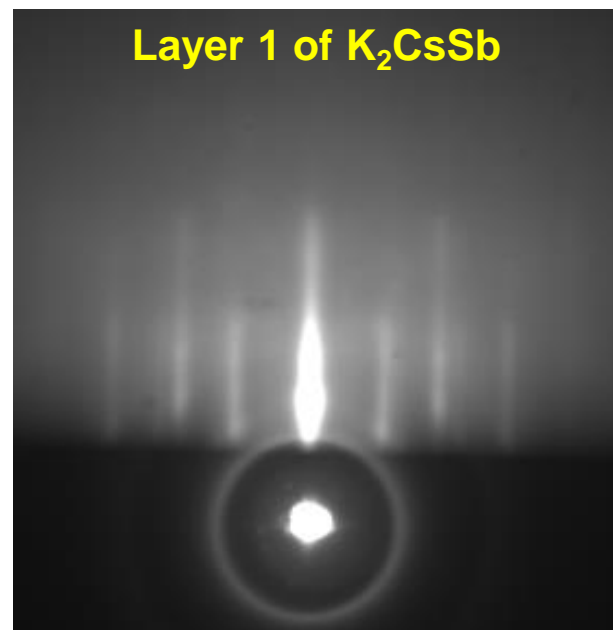
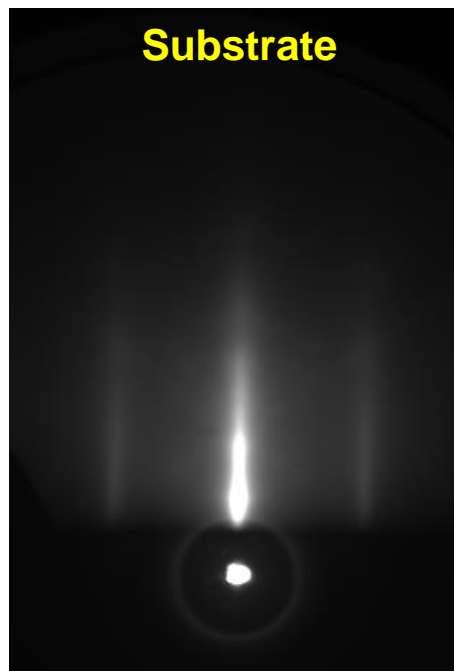
Calculated atomic compositions

	K	Sb	Cs
L005 Si	2.37	1.00	0.91
L006 Si	2.21	1.00	0.95
L011 Si	2.07	1.00	0.94
L012 MgO	1.98	1.00	0.88

Good K/Cs/Sb ratio!



RHEED of K_2CsSb /New Substrate (Sample-2)



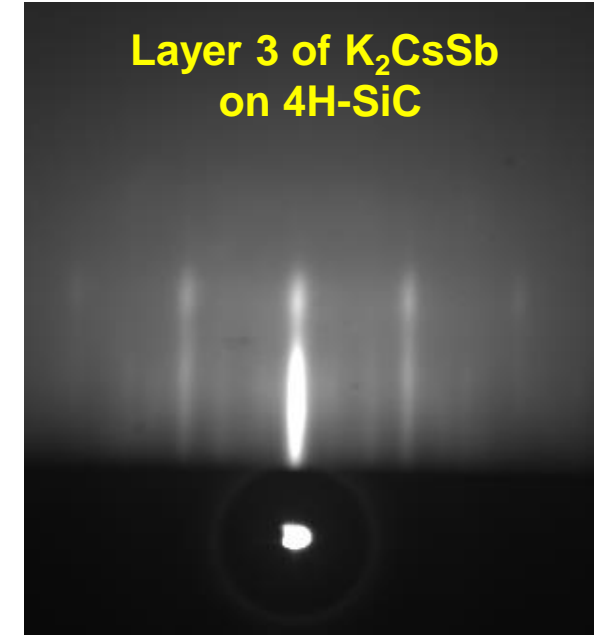
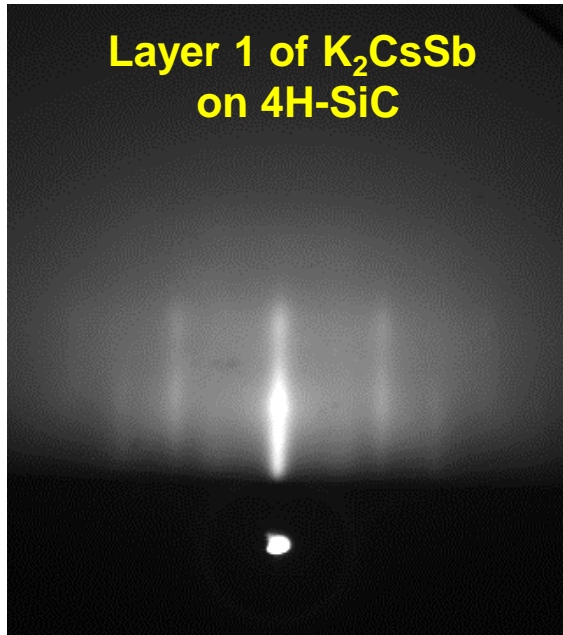
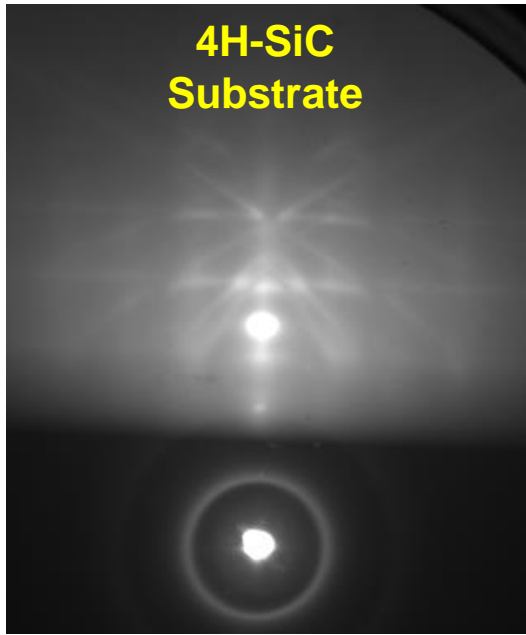
RHEED of K_2CsSb

- RHEED image shows epitaxial growth.
- Streaks represent smooth surfaces with small domains.
- Dots represents 3D islands.

K_2CsSb on Substrate

Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	34.55	4.96	111
2 nd	59	2.91	122
3 rd	69.25	2.48	222
4 th	90.4	1.90	133

RHEED of $K_2CsSb/4H-SiC$ (Sample -3): Sb deposited using thermal evaporation



RHEED of $K_2CsSb/4H-SiC$

- RHEED image shows epitaxial growth.
- Streaks represent smooth surfaces with small domains.

K_2CsSb on 4H-SiC

Peak # from center	D(pixel)	d (Å)	Close to Planes
1 st	38.9	4.41	002
2 nd	58.7	2.92	122
3 rd	74.75	2.29	004
4 th	89.15	1.92	133